

What Is Claimed Is:

1. A transport system within a fabrication system, the fabrication system comprising a plurality of tools for processing articles, the transport system comprising a stocker
5 and a track subsystems, wherein:

the stocker subsystem comprises:

a stocker body for storing the articles;

a plurality of load ports, located on the stocker
10 body, enabling the articles to be transferred
between the stocker body and the track
subsystem, the number of which depends on
properties of the tools; and

the track subsystem comprises a delivery part and a load
15 part, comprising a plurality of branches
corresponding to the load ports.

2. The transport system as claimed in claim 1, wherein
the articles are semiconductor wafers.

3. The transport system as claimed in claim 1, wherein
the stocker body further comprises an outward load port enabling
20 the articles to be transferred between the stocker body and an
outside system.

4. The transport system as claimed in claim 3, wherein
the outward load port, linked with one of the branches, enables
the articles to be transferred between the stocker body and the
25 track subsystem.

5. A fabrication system, comprising:

a plurality of tools for processing articles; and

a transport system comprising a stocker subsystem and a track subsystem, wherein:

the stocker subsystem comprises:

a stocker body for storing the articles;

5 a plurality of load ports, located on the stocker body, enabling the articles to be transferred between the stocker body and the track subsystem, the number of load ports depending on properties of the tools; and

10 the track subsystem comprises delivery and load parts, the load parts comprising a plurality of branches corresponding to the load ports.

6. The fabrication system as claimed in claim 5, wherein
15 the articles are semiconductor wafers.

7. The fabrication system as claimed in claim 5, wherein the stocker body further comprises an outward load port enabling the articles to be transferred between the stocker body and an outside system.

20 8. The fabrication system as claimed in claim 7, wherein the outward load port, linked with one of the branches, enables the articles to be transferred between the stocker body and the track subsystem.

9. A fabrication system, comprising:
25 a plurality of tool bays, each of which comprises a plurality of tools for processing articles;

a plurality of intrabay transport systems, each of which
is dedicated to transporting articles within each
tool bay;

a plurality of stocker systems, each of which corresponds
to one of the tool bays and is linked the intrabay
transport system thereof, comprising:

a stocker body for storing the articles; and
an intrabay load port, located on the stocker body,
enabling the articles to be transferred between
the stocker body and corresponding intrabay
transport system; and

a plurality of interbay load ports, located on the
stocker body, enabling the articles to be
transferred between the stocker bodies
corresponding to different tool bays; and

an interbay transport system, linking the tool bays for
transporting the articles between the tool bays,
comprising delivery and load parts, wherein the load
part comprises a plurality of branches corresponding
to the load ports.

10. The fabrication system as claimed in claim 9, wherein
the articles are semiconductor wafers.

11. The fabrication system as claimed in claim 9, wherein
the intrabay load port, linked with one of the branches, enables
the articles to be transferred between the stocker body and
corresponding intrabay transport system.

12. A transport method for controlling article transport
in a fabrication system, wherein the fabrication system

comprises a plurality of tools and a transport system comprising
stocker and track subsystems, wherein the stocker subsystem
comprises a stocker body with a plurality of load ports, and the
track subsystem comprises delivery and load parts with a
5 plurality of branches corresponding to the load ports, the
method comprising:

determining the targeted tool of the articles;

determining a load port and corresponding branch to deliver
the articles in accordance with the status of the
10 targeted tool, the load parts, and the load ports;
and

issuing a transport demand to direct the transport system
to transport the articles in accordance with the
route.

15 13. The transport method as claimed in claim 12, wherein
the articles are semiconductor wafers.

14. A storage medium for storing a computer program
providing a transport method for controlling article transport
in a fabrication system, wherein the fabrication system
20 comprises a plurality of tools and a transport system comprising
a stocker and a track subsystems, wherein the stocker subsystem
comprises a stocker body with a plurality of load ports, and the
track subsystem comprising delivery and load parts with a
plurality of branches corresponding to the load ports, the
25 method comprising:

receiving destination information recording the targeted
tool of the articles;

determining a load port and corresponding branch to receive
the articles in accordance with the status of the

targeted tool, the load parts, and the load ports;
and
issuing a transport demand to direct the transport system
to transport the articles in accordance with the
5 route.

15. The storage medium as claimed in claim 14, wherein the
articles are semiconductor wafers.